## What is claimed is:

- 1 1. An RF passive circuit comprising:
- a semiconductor substrate;
- 3 a spiral inductor which is formed on a main surface
- 4 of the semiconductor substrate;
- a via-hole which is formed at a position adjacent to
- 6 the spiral inductor by applying a metal film on an inside
- 7 wall of a hole provided through the semiconductor
- 8 substrate;
- 9 a dielectric layer which is formed on the metal film;
- 10 and
- a wiring metal layer which is formed on the dielectric
- 12 layer and holds a capacitor between the via-hole;
- wherein one end of the spiral inductor extends to be
- 14 connected with the wiring metal layer.
  - 1 2. The RF passive circuit of Claim 1,
- wherein the spiral inductor has a double layer
- 3 structure having an upper wiring metal layer and a lower
- 4 wiring metal layer, where at least one of the wiring metal
- 5 layers is in a spiral pattern, and where the wiring metal
- 6 layers are connected to each other, with a contact hole
- 7 therebetween.

- 1 3. An RF choke used in at least one of a matching circuit
- 2 and a bias feeding circuit, both circuits being included
- 3 in an RF amplifier, the RF choke comprising:
- a semiconductor substrate where at least one of the
- 5 matching circuit and the bias feeding circuit is
- 6 incorporated;
- 7 a spiral inductor which is formed on a main surface
- 8 of the semiconductor substrate;
- 9 a via-hole which is formed at a position adjacent to
- 10 the spiral inductor by applying a metal film on an inside
- 11 wall of a hole provided through the semiconductor
- 12 substrate;
- a dielectric layer which is formed on the metal film;
- 14 and
- a wiring metal layer which is formed on the dielectric
- 16 layer and holds a capacitor between the via-hole,
- wherein one end of the spiral inductor extends to be
- 18 connected with the wiring metal layer.
- 1 4. An RF passive circuit comprising:
- 2 a semiconductor substrate;
- 3 a spiral inductor which is formed on a main surface
- 4 of the semiconductor substrate;
- 5 a via-hole which is formed at a position adjacent to

- 6 the spiral inductor by applying a metal film on an inside
- 7 wall of a hole provided through the semiconductor
- 8 substrate;
- a first wiring metal layer which is formed on a first
- 10 dielectric layer and equivalently forms a first capacity
- 11 element between the via-hole; and
- 12 a second wiring metal layer which is formed on the
- 13 first wiring metal layer with a second dielectric layer
- 14 therebetween, and equivalently forms a second capacity
- 15 element between the first wiring metal layer,
- wherein the via-hole and the second wiring metal
- 17 layer are electrically connected to be able to hold a static
- 18 capacity determined by a sum of the first capacity element
- 19 and the second capacity element,
- 20 and wherein one end of the spiral inductor further
- 21 extends so as to be electrically connected to the first
- 22 wiring metal layer.
  - 1 5. The RF passive circuit of Claim 4,
- wherein the spiral inductor has a double layer
- 3 structure having an upper wiring metal layer and a lower
- 4 wiring metal layer, where at least one of the wiring metal
- 5 layers is in a spiral pattern, and where the wiring metal
- 6 layers are connected to each other, with a contact hole

- 7 therebetween.
- 1 6. An RF choke used in at least one of a matching circuit
- 2 and a bias feeding circuit, both circuits being included
- 3 in an RF amplifier, the RF choke comprising:
- a semiconductor substrate where at least one of the
- 5 matching circuit and the bias feeding circuit is
- 6 incorporated;
- 7 a spiral inductor which is formed on a main surface
- 8 of the semiconductor substrate;
- 9 a via-hole which is formed at a position adjacent to
- 10 the spiral inductor by applying a metal film on an inside
- 11 wall of a hole provided through the semiconductor
- 12 substrate;
- a first wiring metal layer which is formed on a first
- 14 dielectric layer and equivalently forms a first capacity
- 15 element between the via-hole; and
- a second wiring metal layer which is formed on the
- 17 first wiring metal layer with a second dielectric layer
- 18 therebetween, and equivalently forms a second capacity
- 19 element between the first wiring metal layer,
- wherein the via-hole and the second wiring metal
- 21 layer are electrically connected to be able to hold a static
- 22 capacity determined by a sum of the first capacity element

- 23 and the second capacity element,
- 24 and wherein one end of the spiral inductor further
- 25 extends so as to be electrically connected to the first
- 26 wiring metal layer.
  - 1 7. An RF passive circuit comprising:
- 2 a semiconductor substrate;
- a via-hole which is formed by applying a metal film
- 4 on an inside wall of a hole provided through the
- 5 semiconductor substrate;
- 6 a wiring metal layer which is formed on a main surface
- 7 of the semiconductor substrate and is electrically
- 8 connected to the via-hole; and
- 9 an inductor which is made of a metal film in a spiral
- 10 pattern and is formed on the first wiring metal layer with
- 11 a dielectric layer therebetween.
- 1 8. The RF passive circuit of Claim 7,
- wherein the wiring metal layer is in the same parallel
- 3 pattern as the inductor.
- 1 9. An RF choke used in at least one of a matching circuit
- 2 and a bias feeding circuit, both circuits being included
- 3 in an RF amplifier, the RF choke comprising:

- a semiconductor substrate where at least one of the
- 5 matching circuit and the bias feeding circuit is
- 6 incorporated;
- 7 a via-hole which is formed by applying a metal film
- 8 on an inside wall of a hole provided through the
- 9 semiconductor substrate;
- 10 a wiring metal layer which is formed on a main surface
- 11 of the semiconductor substrate and is electrically
- 12 connected to the via-hole; and
- an inductor which is made of a metal film in a spiral
- 14 pattern and is formed on the first wiring metal layer with
- 15 a dielectric layer therebetween.
- 1 10. An RF passive circuit comprising:
- 2 a semiconductor substrate;
- a via-hole which is formed by applying a metal film
- 4 on an inside wall of a hole provided through the
- 5 semiconductor substrate;
- a dielectric layer which is formed on a main surface
- 7 of the semiconductor substrate so as to cover the metal
- 8 film; and
- 9 an inductor which is a spirally-formed metal layer
- 10 formed on the dielectric layer, which forms a static
- 11 capacity where one part thereof faces the metal film of

- 12 the via-hole.
- 1 11. An RF choke used in at least one of a matching circuit
- 2 and a bias feeding circuit, both circuits being included
- 3 in an RF amplifier, the RF choke comprising:
  - a semiconductor substrate where at least one of the
  - 5 matching circuit and the bias feeding circuit is
  - 6 incorporated;
  - 7 a via-hole which is formed by applying a metal film
  - 8 on an inside wall of a hole provided through the
  - 9 semiconductor substrate;
- 10 a dielectric layer which is formed on a main surface
- 11 of the semiconductor substrate so as to cover the metal
- 12 film; and
- an inductor which is a spirally-formed metal layer
- 14 formed on the dielectric layer, which forms a static
- 15 capacity where one part thereof faces the metal film of
- 16 the via-hole.
- 1 12. An RF passive circuit comprising:
- 2 a semiconductor substrate;
- 3 a dielectric layer which is formed on a first main
- 4 surface of the semiconductor substrate;
- 5 a via-hole which is formed by applying a metal film

- 6 on an inside wall of a hole provided through a second main
- 7 surface of the semiconductor substrate until the hole
- 8 reaches the dielectric layer; and
- 9 a metal layer formed on the dielectric layer which
- 10 holds a static capacity between the metal film of the
- 11 via-hole and the metal layer.
- 1 13. The RF passive circuit of Claim 12, further
- 2 comprising:
- 3 a resistance element whose one terminal is
- 4 electrically connected to the metal layer, and the other
- 5 terminal to the via-hole.
- 1 14. An RF amplifier comprising:
- 2 a semiconductor substrate;
- 3 a dielectric layer which is formed on a first main
- 4 surface of the semiconductor substrate;
- 5 a via-hole which is formed by applying a metal film
- 6 on an inside wall of a hole provided through a second main
- 7 surface of the semiconductor substrate until the hole
- 8 reaches the dielectric layer;
- 9 a metal layer formed on the dielectric layer which
- 10 holds a static capacity between the metal film of the
- 11 via-hole and the metal layer; and

- a field effective transistor, mounted on the
- 13 semiconductor substrate, which has a common gate circuit
- 14 having a gate terminal electrically connected to the metal
- 15 layer.
  - 1 15. An RF amplifier comprising:
  - 2 a semiconductor substrate;
  - 3 a dielectric layer which is formed on a first main
  - 4 surface of the semiconductor substrate;
  - 5 a via-hole which is formed by applying a metal film
  - 6 on an inside wall of a hole provided through a second main
  - 7 surface of the semiconductor substrate until the hole
  - 8 reaches the dielectric layer;
  - 9 a metal layer formed on the dielectric layer which
- 10 holds a static capacity between the metal film of the
- 11 via-hole and the metal layer; and
- a bipolar transistor, mounted on the semiconductor
- 13 substrate, which has a common base circuit having a base
- 14 terminal electrically connected to the metal layer.
  - 1 16. An RF amplifier comprising:
- 2 a semiconductor substrate;
- 3 a dielectric layer which is formed on a first main
- 4 surface of the semiconductor substrate;

- 5 a via-hole which is formed by applying a metal film
- 6 on an inside wall of a hole provided through a second main
- 7 surface of the semiconductor substrate until the hole
- 8 reaches the dielectric layer;
- 9 a metal layer formed on the dielectric layer which
- 10 holds a static capacity between the metal film of the
- via-hole and the metal layer;
- 12 a resistance element whose one terminal is
- 13 electrically connected to the via-hole and the other
- 14 terminal to the metal layer; and
- a field effective transistor mounted on the
- 16 semiconductor substrate whose source terminal is connected
- 17 to the other terminal of the resistance element connected
- 18 to the metal layer, so as to form a self bias circuit.
- 1 17. An RF passive circuit comprising:
- 2 a semiconductor substrate;
- a via-hole which is formed by applying a metal film
- 4 on an inside wall of a hole provided through the
- 5 semiconductor substrate;
- a dielectric layer which is formed on an inside wall
- 7 of the via-hole; and
- 8 a wiring metal layer formed on the dielectric layer,
- 9 which holds a static capacity between the via-hole.

- 1 18. The RF passive circuit of Claim 17, further
- 2 comprising:
- 3 a resistance element whose one terminal is
- 4 electrically connected to the metal film of the via-hole,
- 5 and the other terminal to the wiring metal layer.
- 1 19. An RF amplifier comprising:
- 2 a semiconductor substrate;
- 3 a via-hole which is formed by applying a metal film
- 4 on an inside wall of a hole provided through the
- 5 semiconductor substrate;
- a dielectric layer which is formed on an inside wall
- 7 of the via-hole;
- 8 a wiring metal layer formed on the dielectric layer,
- 9 which holds a static capacity between the via-hole; and
- a field effective transistor, mounted on the
- 11 semiconductor substrate, which has a common gate circuit
- 12 having a gate terminal electrically connected to the wiring
- 13 metal layer.
- 1 20. An RF amplifier comprising:
- 2 a semiconductor substrate;
- a via-hole which is formed by applying a metal film
- 4 on an inside wall of a hole provided through the

- 5 semiconductor substrate;
- a dielectric layer which is formed on an inside wall
- 7 of the via-hole;
- 8 a wiring metal layer formed on the dielectric layer,
- 9 which holds a static capacity between the via-hole; and
- a bipolar transistor, mounted on the semiconductor
- 11 substrate, which has a common base circuit having a base
- 12 terminal electrically connected to the wiring metal layer.
  - 1 21. An RF amplifier comprising:
- 2 a semiconductor substrate;
- 3 a via-hole which is formed by applying a metal film
- 4 on an inside wall of a hole provided through the
- 5 semiconductor substrate;
- 6 a dielectric layer which is formed on an inside wall
- 7 of the via-hole;
- 8 a wiring metal layer formed on the dielectric layer,
- 9 which holds a static capacity between the via-hole;
- 10 a resistance element whose one terminal is
- 11 electrically connected to the metal film of the via-hole
- 12 and the other terminal to the metal layer; and
- a field effective transistor mounted on the
- 14 semiconductor substrate whose source terminal is connected
- 15 to the other terminal of the resistance element connected

- 16 to the metal layer, so as to form a self bias circuit.
- 1 22. An RF passive circuit comprising:
- 2 a semiconductor substrate;
- 3 a via-hole which is formed by applying a metal film
- 4 on an inside wall of a hole provided through the
- 5 semiconductor substrate;
- a first dielectric layer which is formed on an inside
- 7 wall of the via-hole;
- 8 a first wiring metal layer formed on the first
- 9 dielectric layer which equivalently forms a first capacity
- 10 element between the via-hole;
- a second dielectric layer which is formed on the first
- 12 wiring metal layer; and
- a second wiring metal layer formed on the second
- 14 dielectric layer which equivalently forms a second
- 15 capacity element between the first wiring metal layer,
- wherein the via-hole and the second wiring metal
- 17 layer are electrically connected, and the sum of static
- 18 capacity of the first capacity element and the second
- 19 capacity element are held between the via-hole and the
- 20 first wiring metal layer.
- 1 23. The RF passive circuit of Claim 22, further

- 2 comprising:
- 3 a resistance element whose one terminal is
- 4 electrically connected either to the second wiring metal
- 5 layer or to the via-hole, and the other terminal to the
- 6 first wiring metal layer.
- 1 24. An RF amplifier comprising:
- 2 a semiconductor substrate;
  - 3 a via-hole which is formed by applying a metal film
  - 4 on an inside wall of a hole provided through the
  - 5 semiconductor substrate;
  - 6 a first dielectric layer which is formed on an inside
  - 7 wall of the via-hole;
  - 8 a first wiring metal layer formed on the first
  - 9 dielectric layer which equivalently forms a first capacity
- 10 element between the via-hole;
- a second dielectric layer which is formed on the first
- 12 wiring metal layer;
- a second wiring metal layer formed on the second
- 14 dielectric layer which equivalently forms a second
- 15 capacity element between the first wiring metal layer,
- the via-hole and the second wiring metal layer being
- 17 electrically connected, and the sum of static capacity of
- 18 the first capacity element and the second capacity element

- 19 being held between the via-hole and the first wiring metal
- 20 layer; and
- 21 a field effective transistor, mounted on the
- 22 semiconductor substrate, which has a common gate circuit
- 23 having a gate terminal electrically connected to the first
- 24 wiring metal layer.
  - 1 25. An RF amplifier comprising:
  - 2 a semiconductor substrate;
  - 3 a via-hole which is formed by applying a metal film
  - 4 on an inside wall of a hole provided through the
  - 5 semiconductor substrate;
  - 6 a first dielectric layer which is formed on an inside
  - 7 wall of the via-hole;
  - 8 a first wiring metal layer formed on the first
  - 9 dielectric layer which equivalently forms a first capacity
- 10 element between the via-hole;
- 11 a second dielectric layer which is formed on the first
- 12 wiring metal layer;
- a second wiring metal layer formed on the second
- 14 dielectric layer which equivalently forms a second
- 15 capacity element between the first wiring metal layer,
- the via-hole and the second wiring metal layer being
- 17 electrically connected, and the sum of static capacity of

- 18 the first capacity element and the second capacity element
- 19 being held between the via-hole and the first wiring metal
- 20 layer; and
- 21 a bipolar transistor, mounted on the semiconductor
- 22 substrate, which has a common base circuit having a base
- 23 terminal electrically connected to the first wiring metal
- 24 layer.
  - 1 26. An RF amplifier comprising:
- 2 a semiconductor substrate;
- 3 a via-hole which is formed by applying a metal film
- 4 on an inside wall of a hole provided through the
- 5 semiconductor substrate;
- 6 a first dielectric layer which is formed on an inside
- 7 wall of the via-hole;
- a first wiring metal layer formed on the first
- 9 dielectric layer which equivalently forms a first capacity
- 10 element between the via-hole;
- ll a second dielectric layer which is formed on the first
- 12 wiring metal layer;
- a second wiring metal layer formed on the second
- 14 dielectric layer which equivalently forms a second
- 15 capacity element between the first wiring metal layer,
- the via-hole and the second wiring metal layer being

- 17 electrically connected, and the sum of static capacity of
- 18 the first capacity element and the second capacity element
- 19 being held between the via-hole and the first wiring metal
- 20 layer;
- 21 a resistance element whose one terminal is
- 22 electrically connected either to the second wiring metal
- 23 layer or to the via-hole, and the other terminal to the
- 24 first wiring metal layer; and
- 25 a field effective transistor mounted on the
- 26 semiconductor substrate whose source terminal is connected
- 27 to the one terminal of the resistance element connected
- 28 either to the second wiring metal layer or to the via-hole,
- 29 so as to form a self bias circuit.